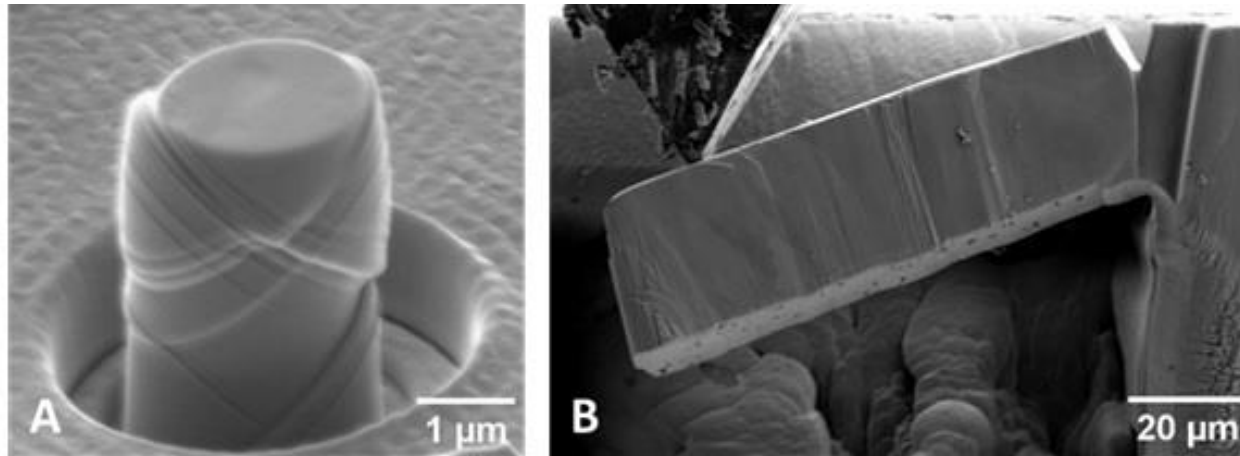


## L'imagerie MEB au service de la (micro)-mécanique



Ronan Henry

[ronan.henry@univ-rouen.fr](mailto:ronan.henry@univ-rouen.fr)

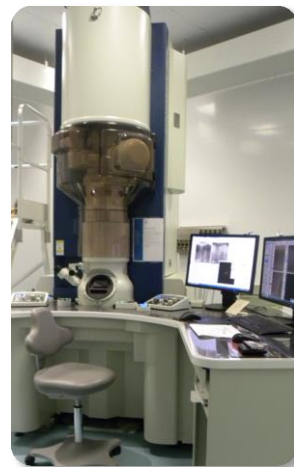
## Le laboratoire

### MEB FIB

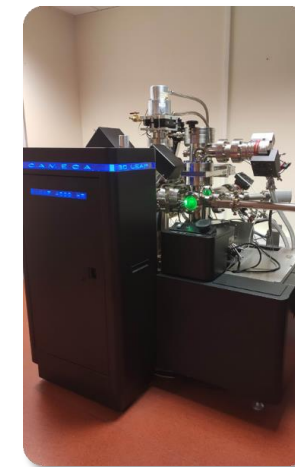


→  
Préparation d'échantillons

### MET



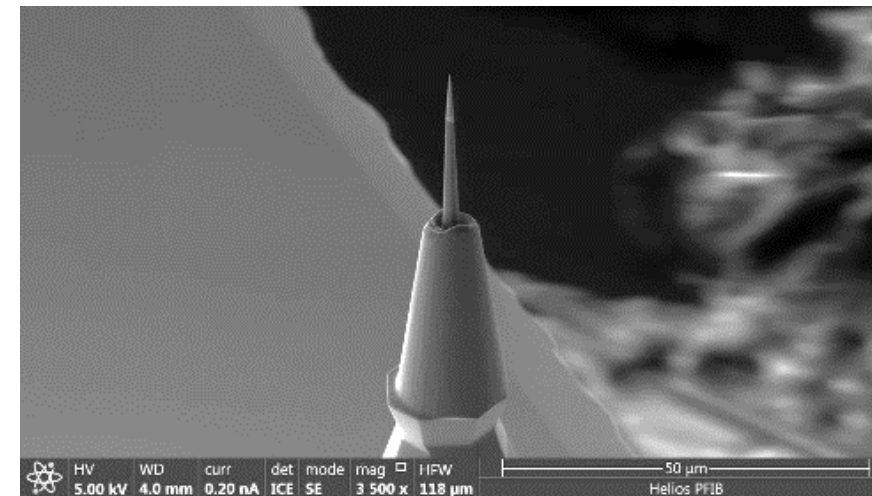
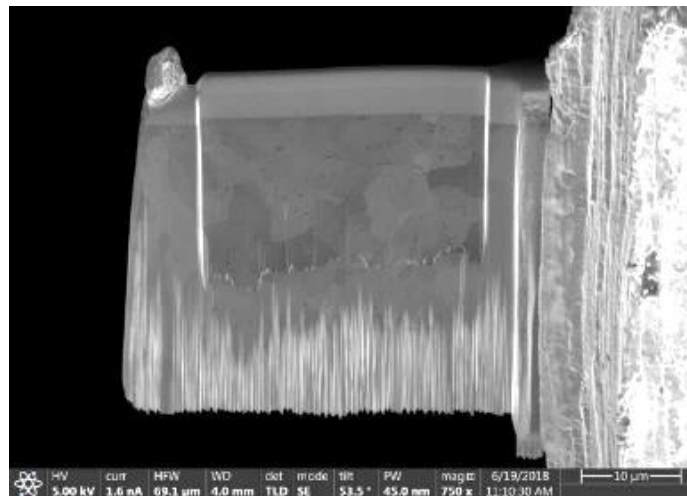
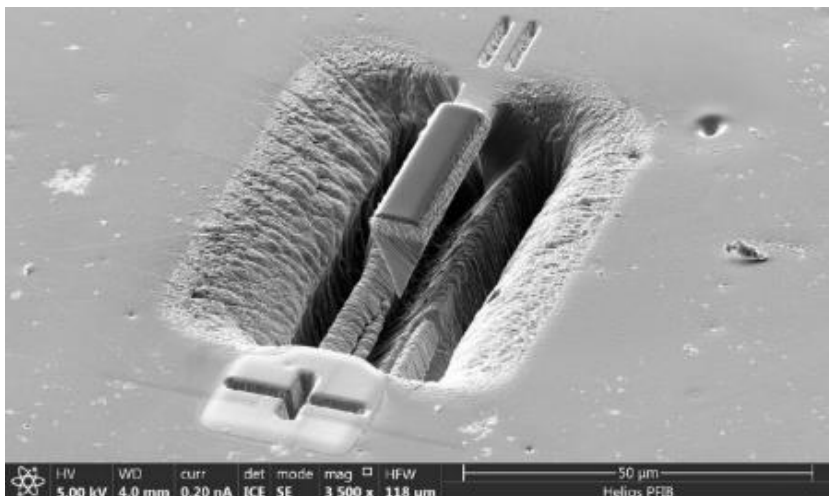
### SAT



### FIB – Usinage

### FIB – Préparation de lame MET

### FIB – Préparation de pointe SAT



MEB/FIB (Focused Ion Beam)*Gallium-FIB Helios G5 UX**Plasma-FIB Xenon Helios G5 CXe**MEB/FIB Gallium Zeiss XB540*

EBSD, EDS...

Platine cryogénique + transfert UHV et/ou cryogénique vers SAT

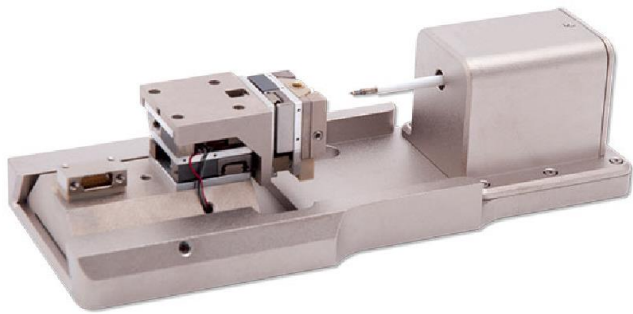
Nucléarisé

For Biological, "Air and/or Moisture Sensitive" Materials analysis :

Battery and fuel cell Research, Catalytic materials, Surface reaction (oxydation, corrosion,...), Thin Films, PV (Selenium based), O(rganic)LED,....



## Essais micro-mécaniques

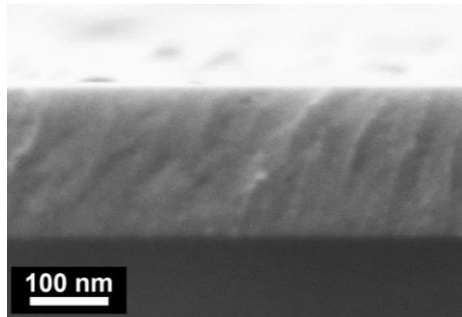


*Bruker Hysitron PI85  
SEM Pico Indenter*

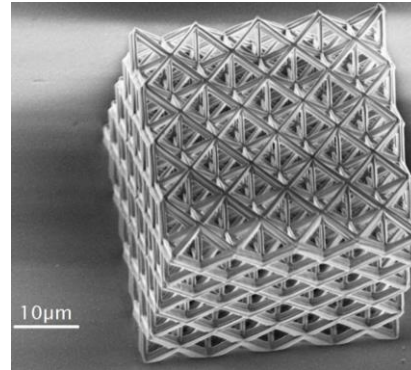


*Placement sur la platine du MEB/FIB*

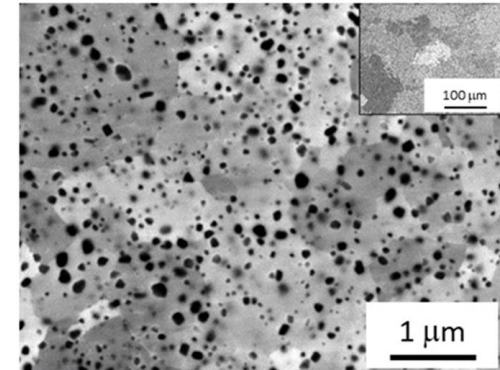
# Introduction



*Revêtements fins*



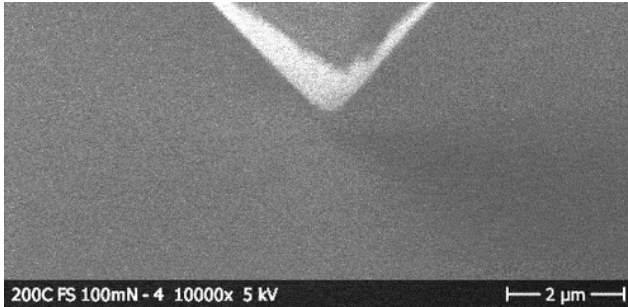
*Miniaturisation*



*Microstructure*

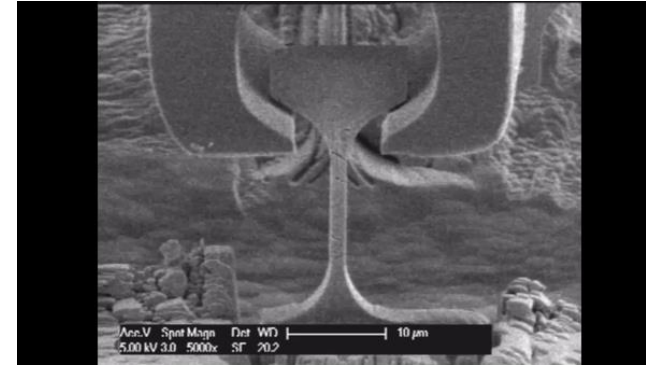
## Essais micromécaniques

### Nano-indentation



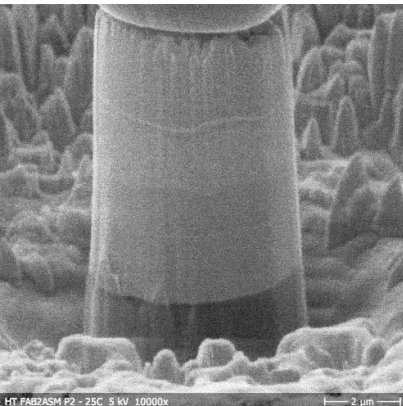
- + Préparation facile
- + Essais rapides
- Analyse complexe
- Quantitatif ?

### Micro-traction



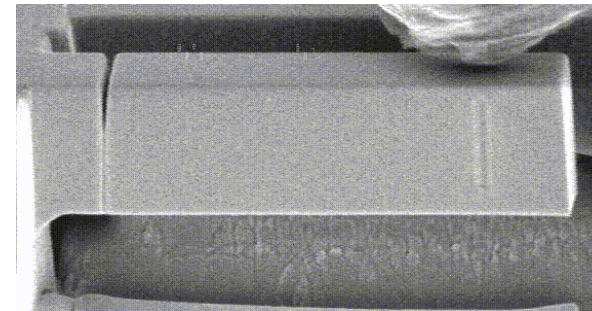
- ++ Analyse
- Préparation
- Essais complexes

### Micro-compression



- + Analyse
- Préparation

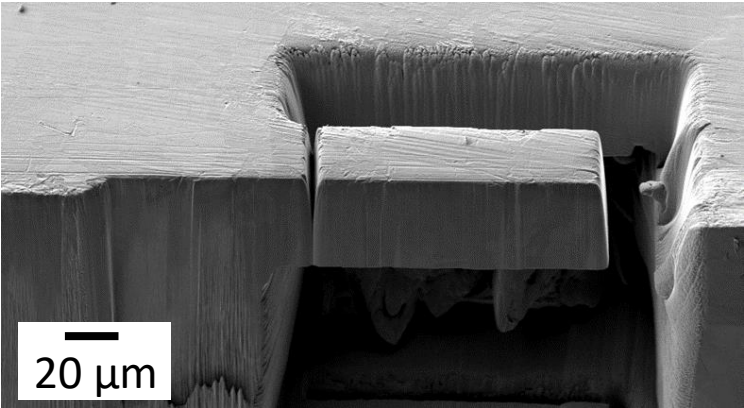
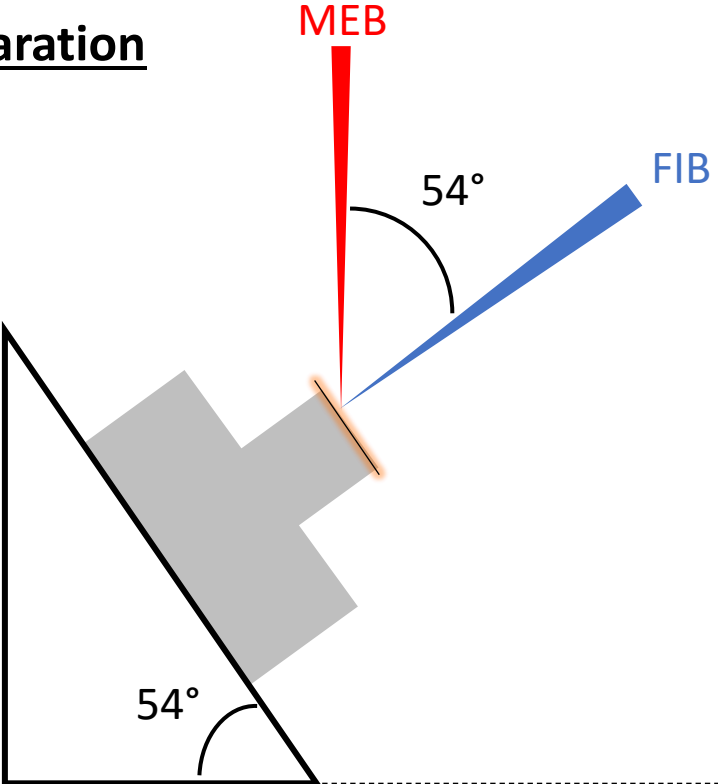
### Micro-flexion



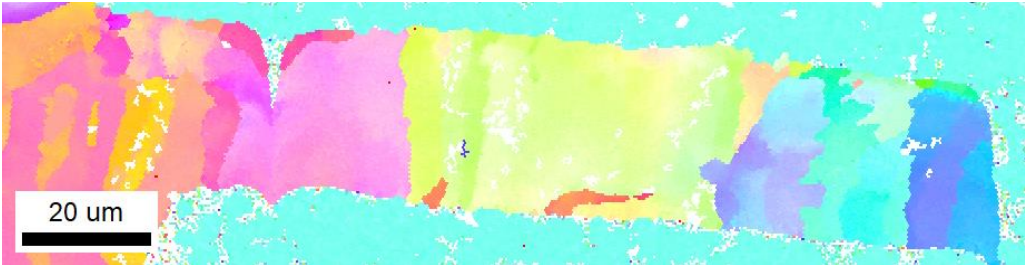
- + Analyse
- Préparation longue
- Essais complexes

# Essais de micro-flexion

## Préparation



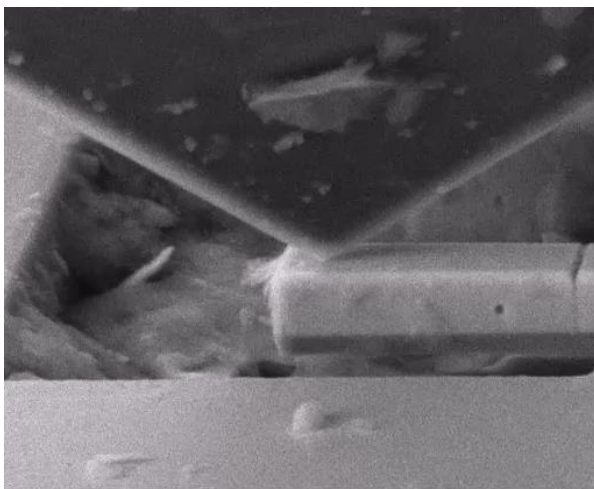
FIB milling



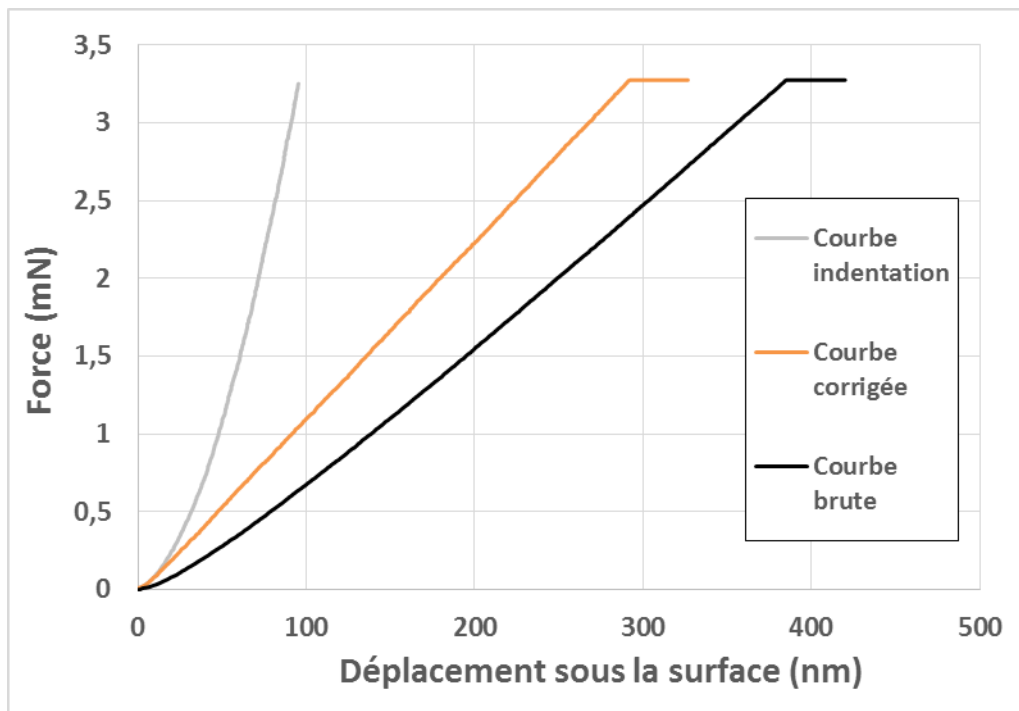
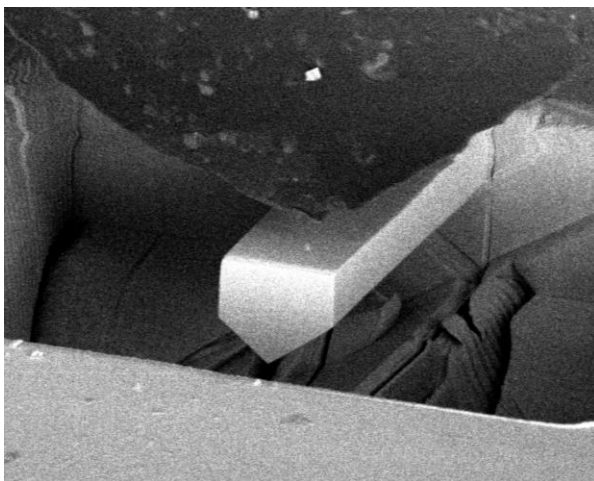
EBSD characterization

Sollicitation

Propagation instable de fissure : imagerie *in situ* peu intéressante



Videos (SEM) of micro-bending test on  $UO_2$  fuels

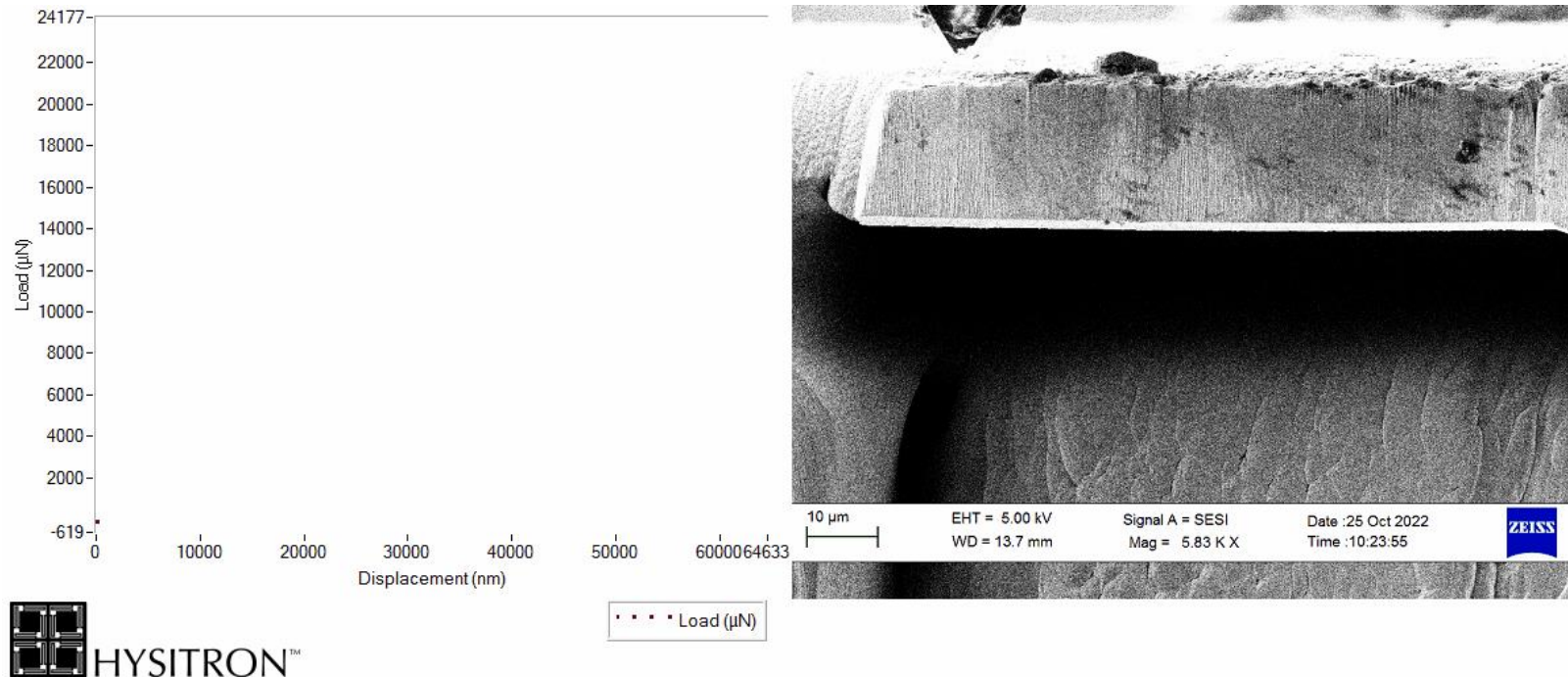


Force-displacement curves recorded in a micro-bending test

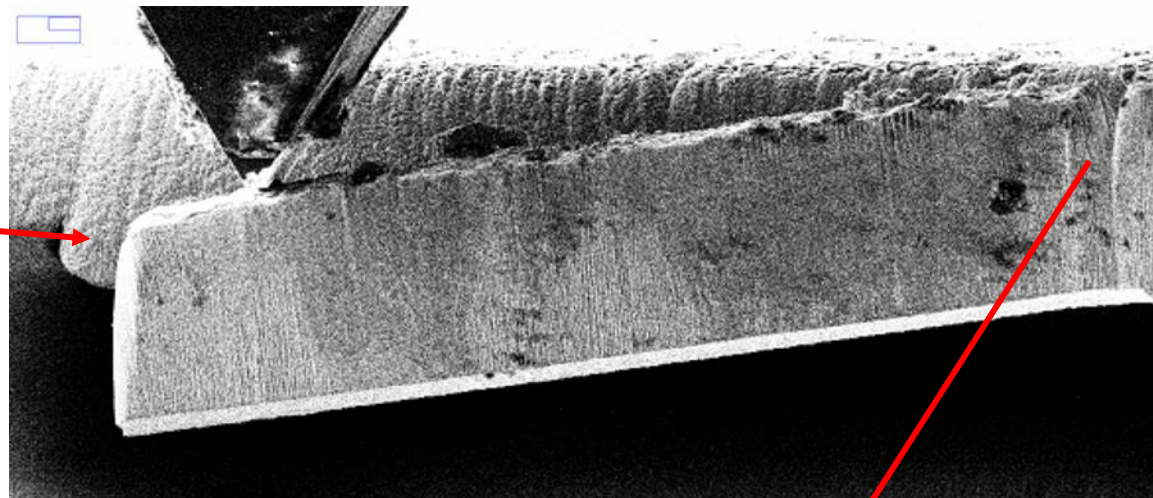
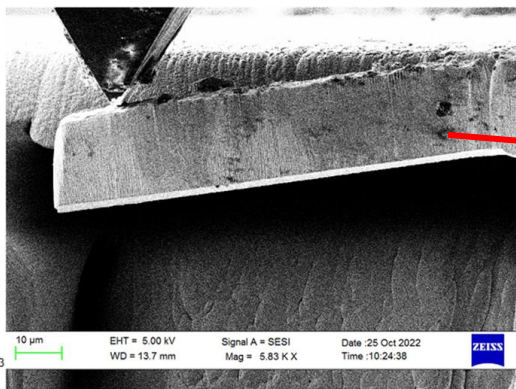
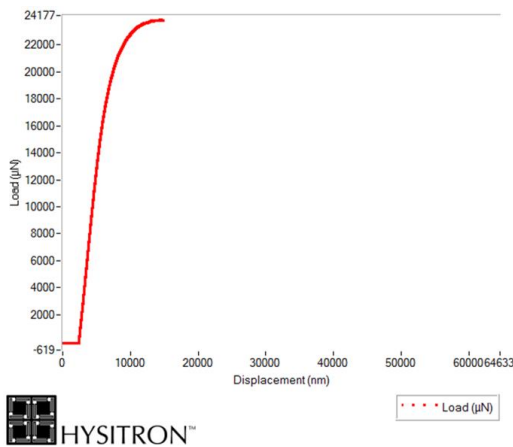
## Flexion *in situ* : film

Propagation stable de fissure : imagerie *in situ* intéressante

- Film : 1919 images et 0,10s/image



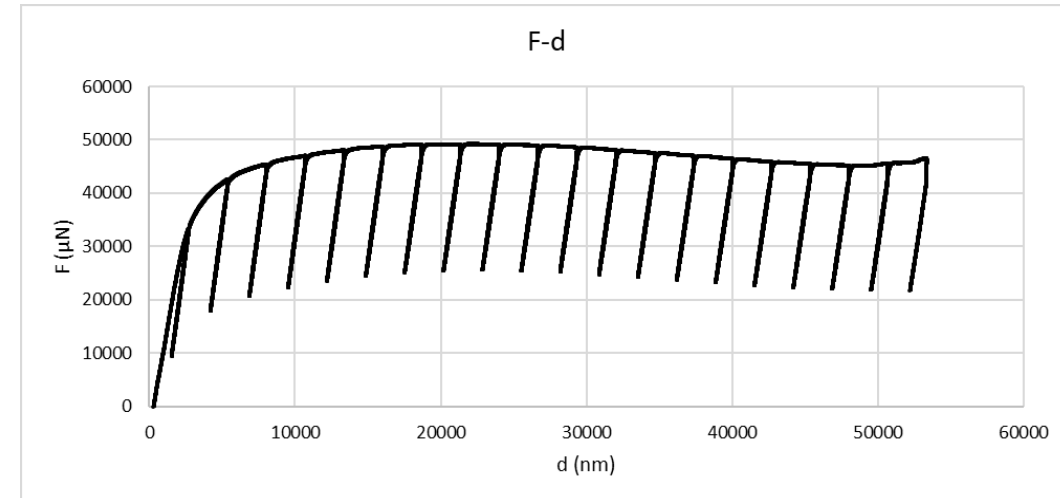
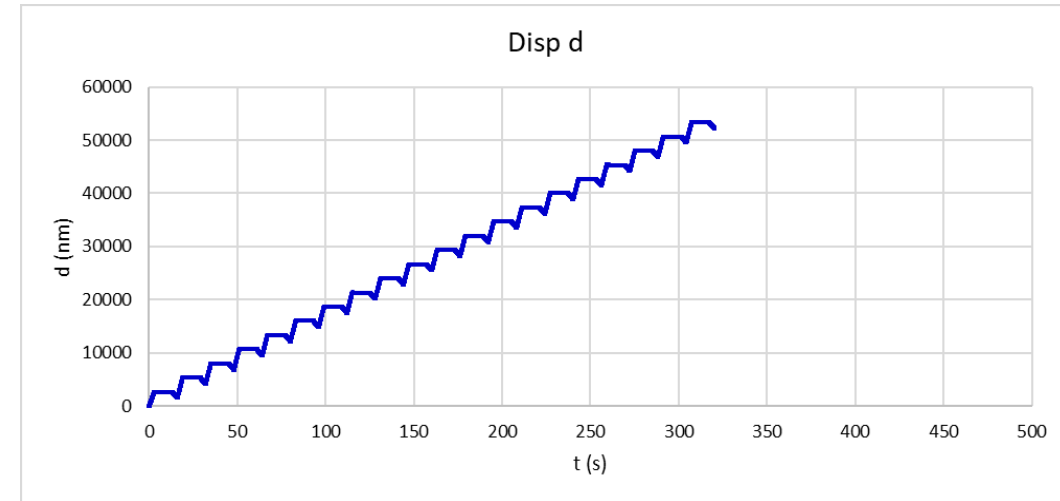
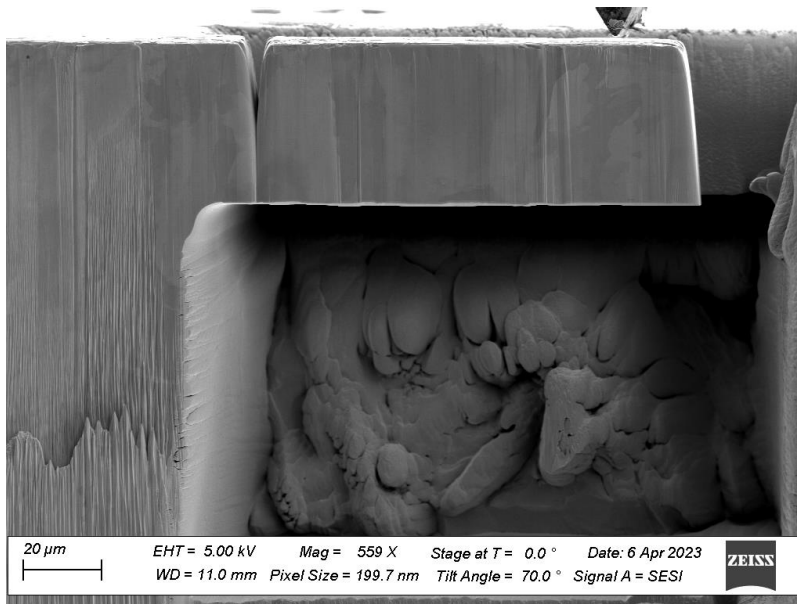
## Flexion *in situ* : film

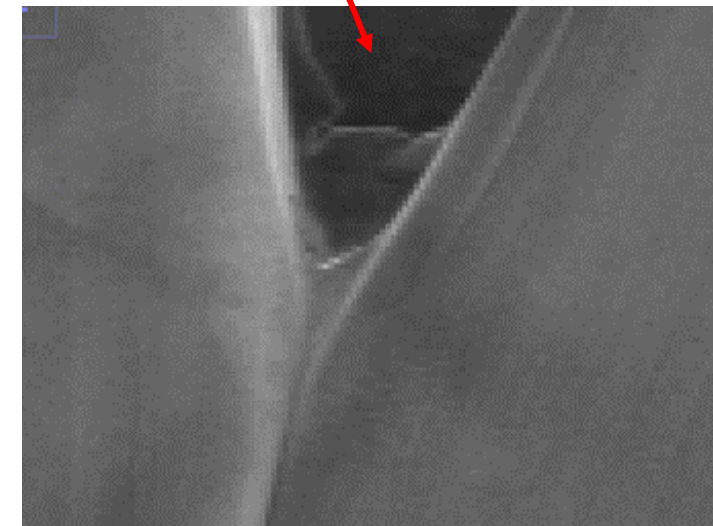
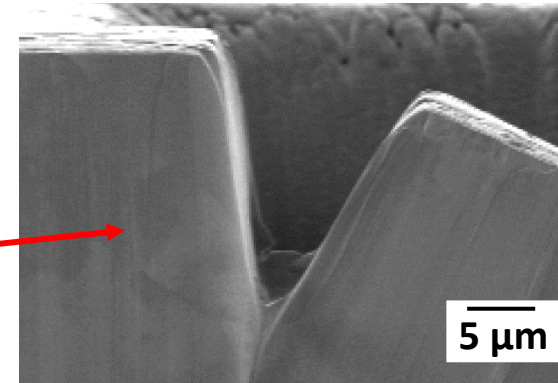
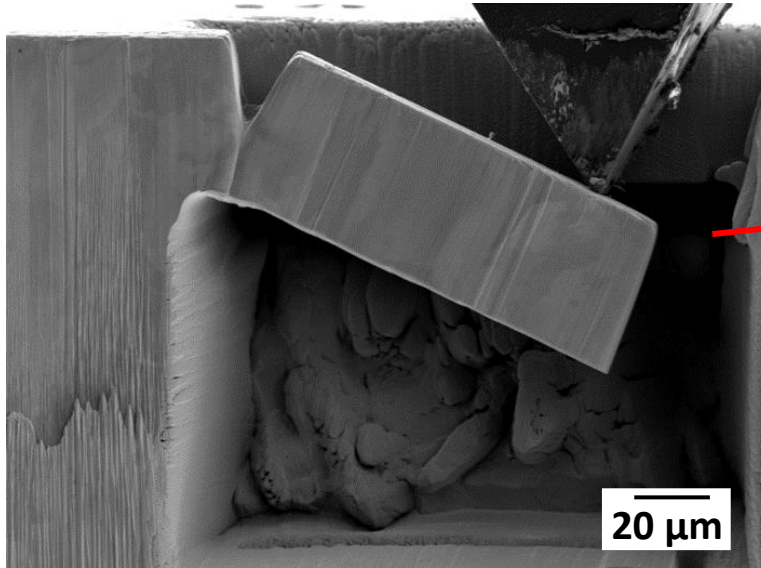


- Beaucoup d'images
- Qualité d'image insuffisante pour suivi correct de fissure

## Flexion *in situ* : pile d'images

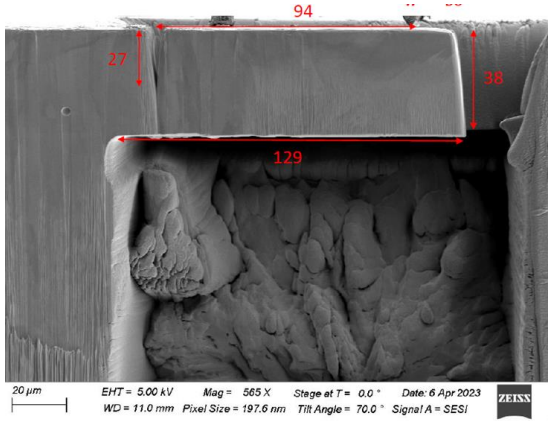
- Pile d'images 50 images et 6s/image
- Sollicitation par paliers : une image/palier



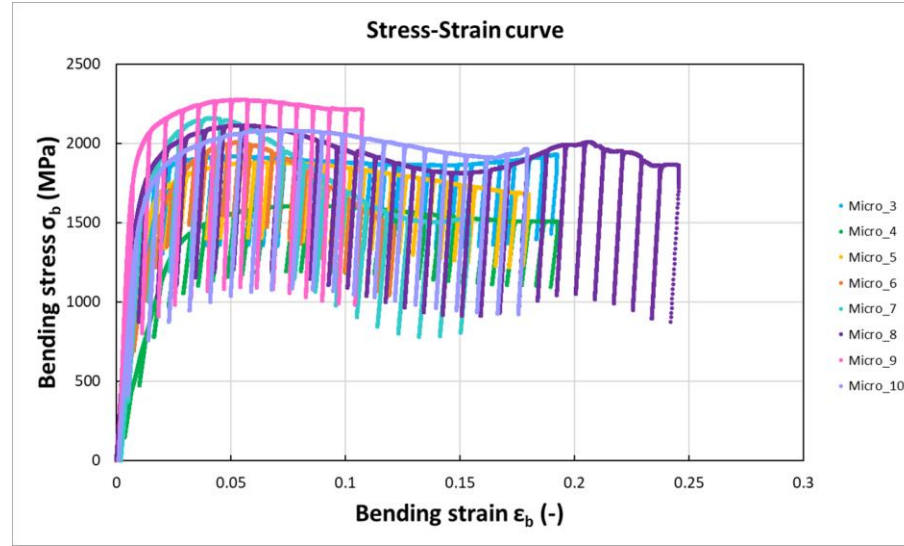
Flexion *in situ* : pile d'images

- Bonne qualité d'image pour suivi de fissure
- Peu d'images

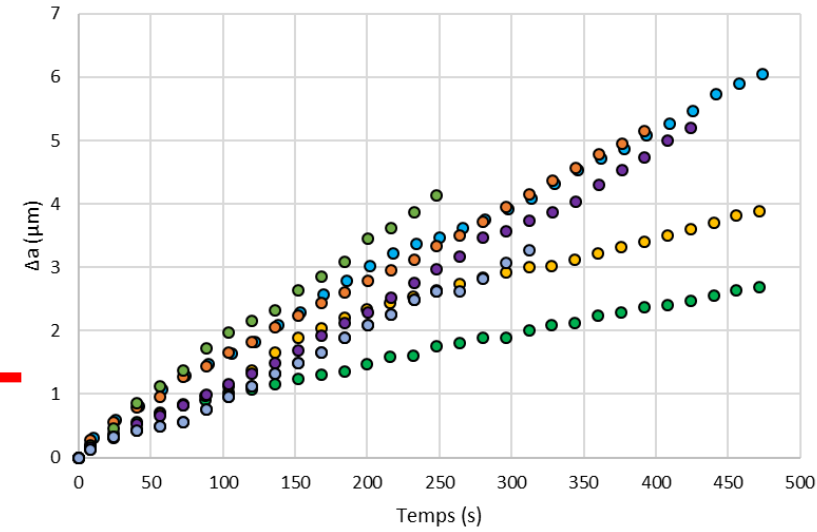
## Flexion *in situ* : pile d'images



+



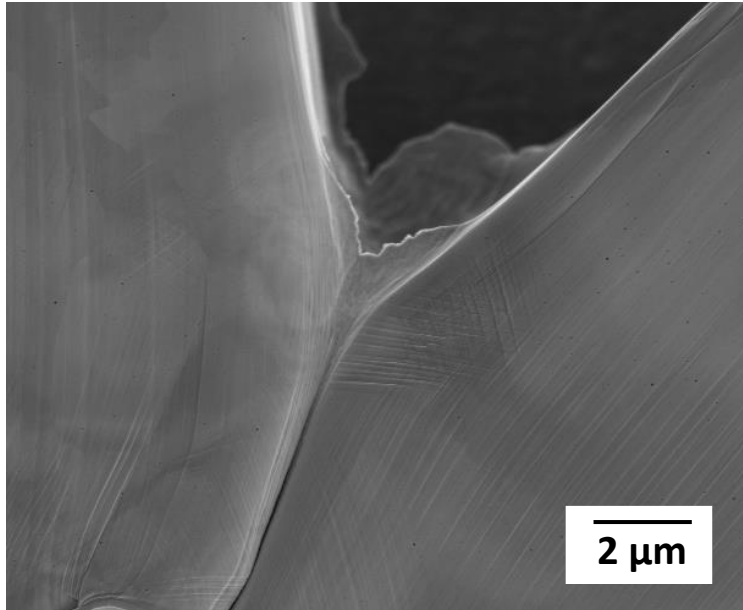
+



Dimensions des éprouvettes

Courbe force-déplacement

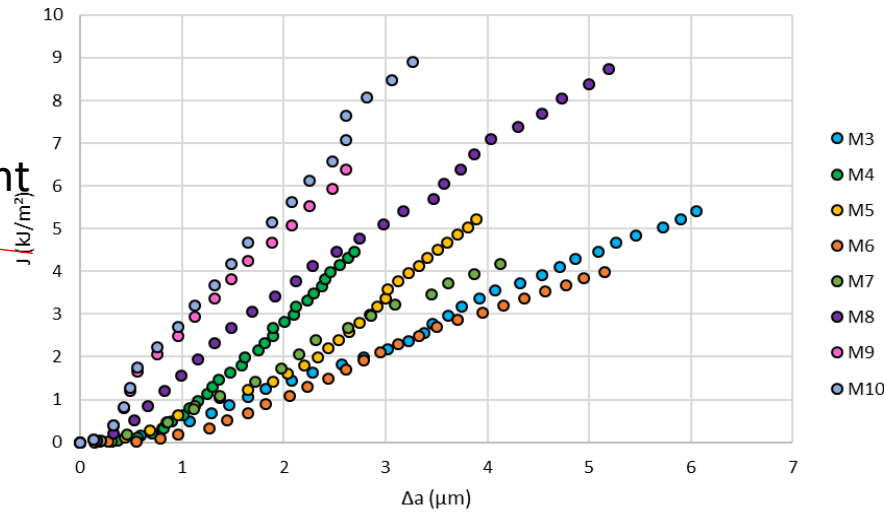
Analyse d'image : longueur de fissure



Émoussement



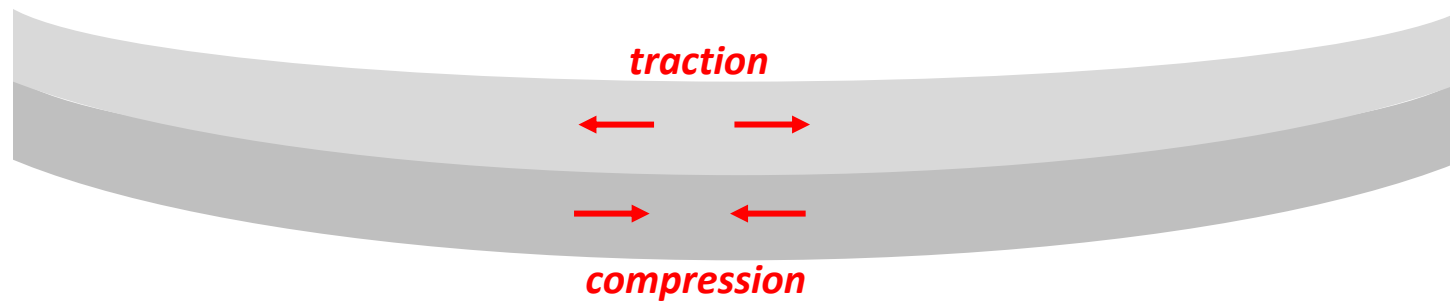
Courbe de résistance (H9067)



## Mesure de contraintes résiduelles :

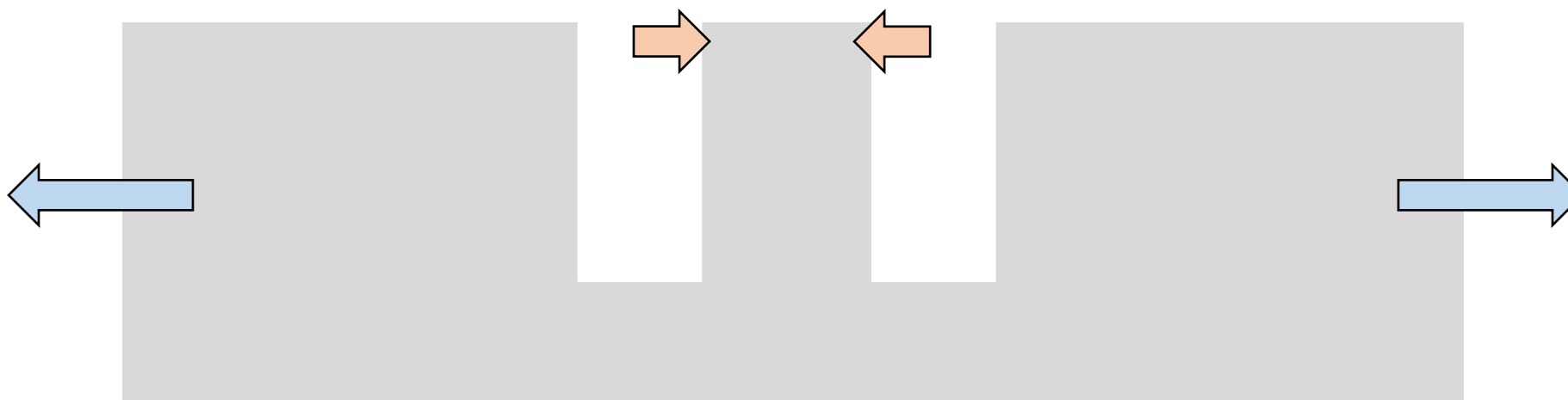
*Mesure de champs de déformation par usinage FIB et Corrélation d'Images Numérique (CIN) d'images MEB*

## Principe



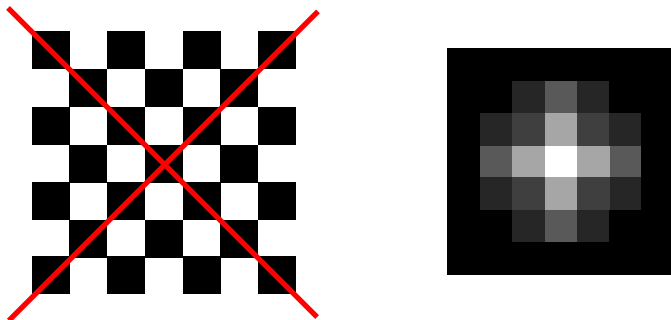
Coefficients de dilatation thermique  $\alpha_1 > \alpha_2$

## Mise en avant

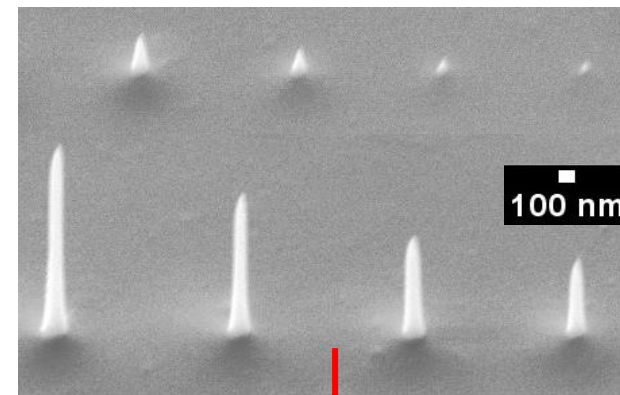


## Mouchetis

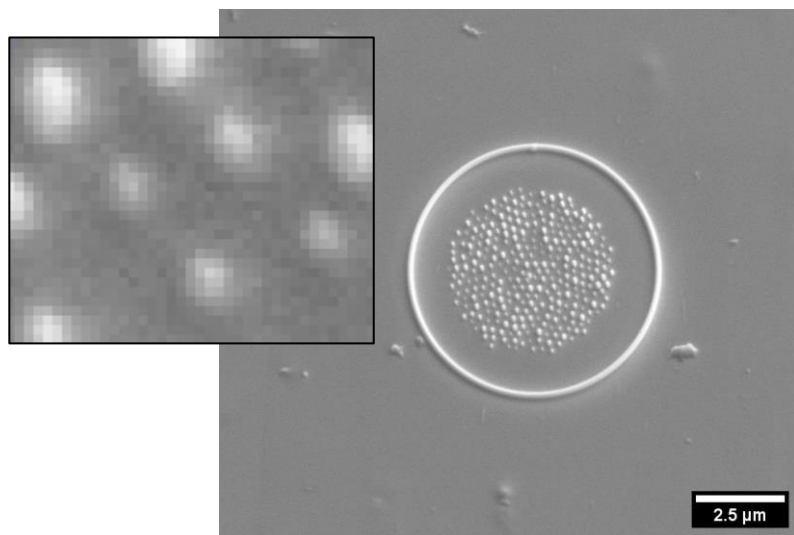
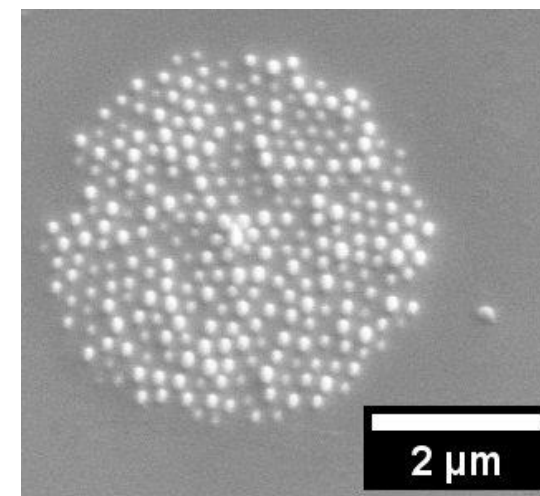
Motif aléatoire, 3 à 5 pixels par particules



Dépôts de platine à 5kV et 200pA / 0,1 à 1s



Logiciel NPVE (FIBICS)

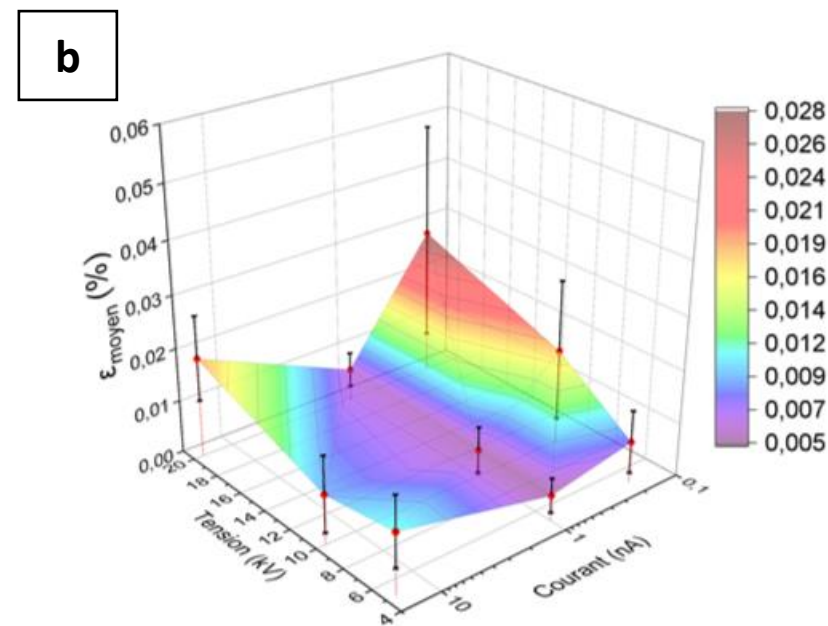
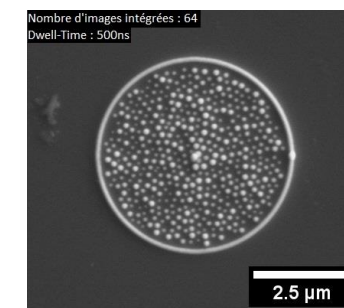
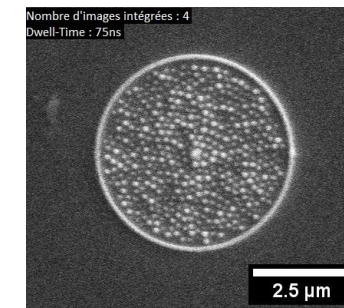
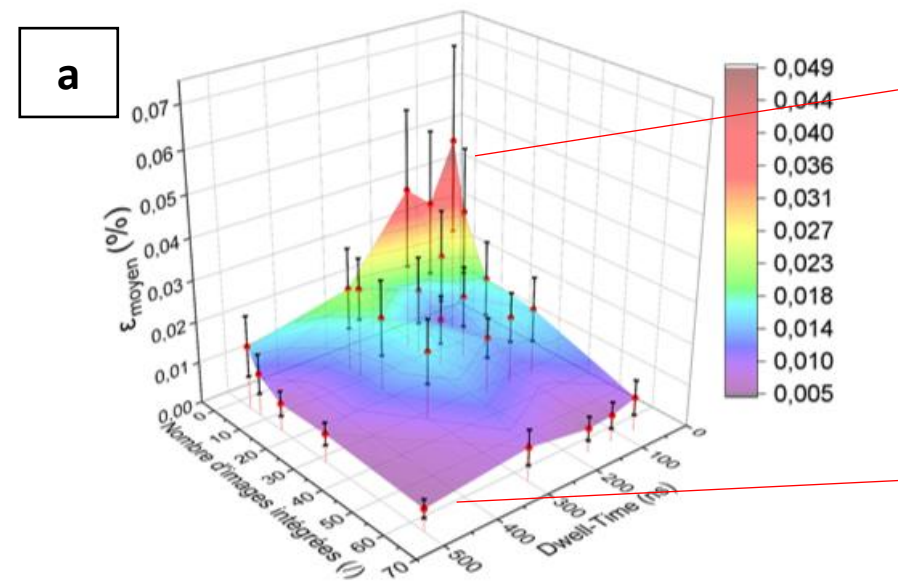
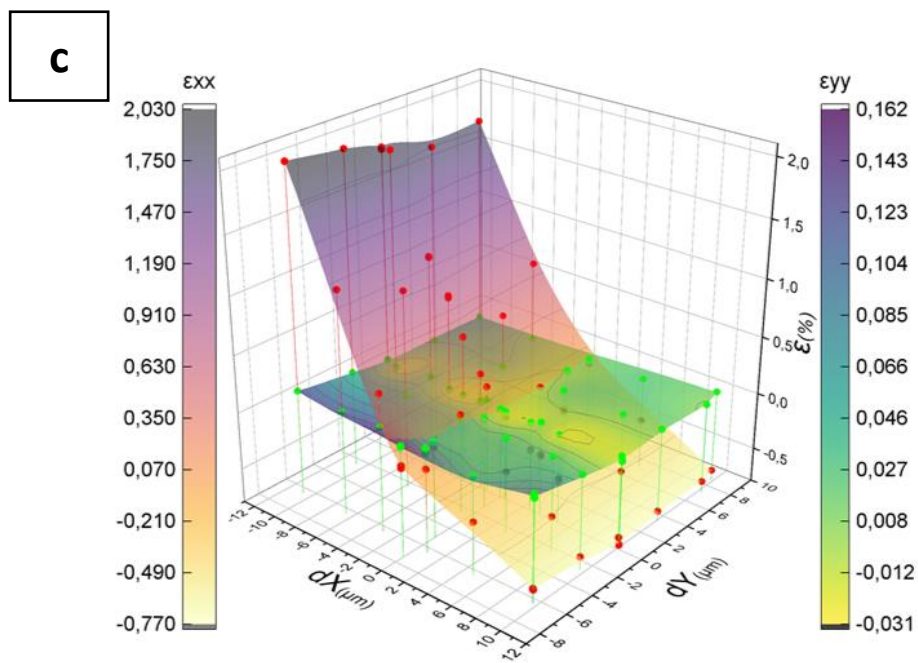


Paramètres dépendent du matériau

Motif aléatoire optimisé

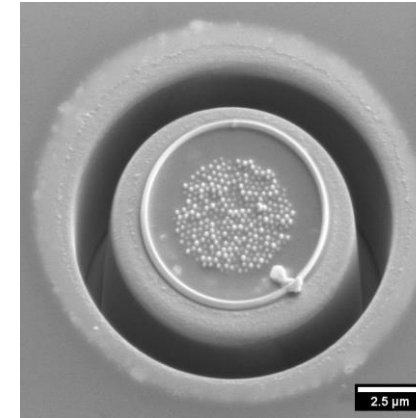
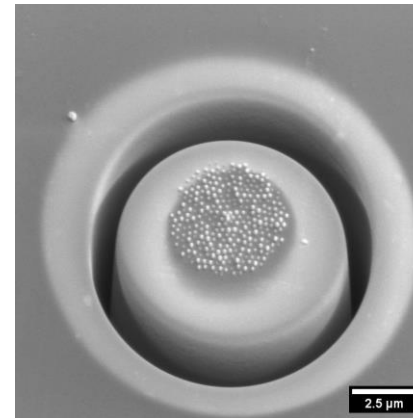
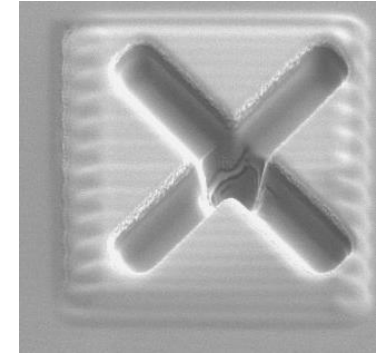
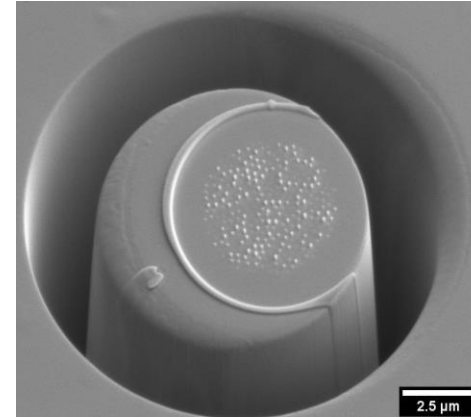
Étude paramétrique

- Mode de réduction du bruit : "frame integer"
- Nombre d'images pour la moyenne (a) : 40
- Dwell time (a) : 100 ns
- Courant (b) : 1 nA
- Tension (b) : 5 kV
- Distorsion (c) : bord de l'image



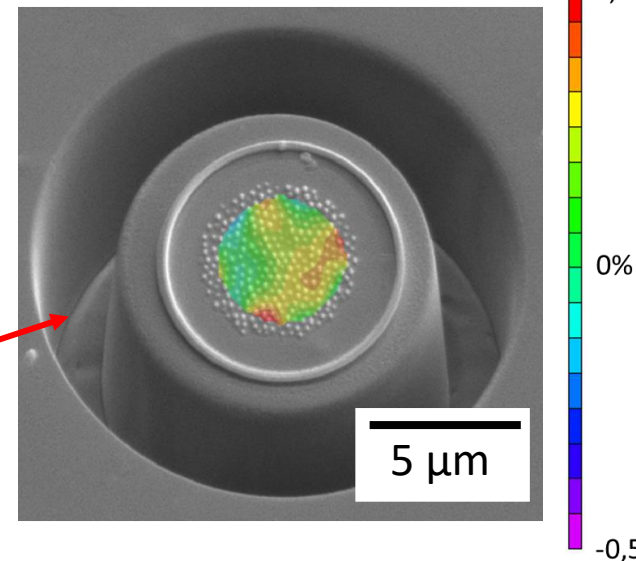
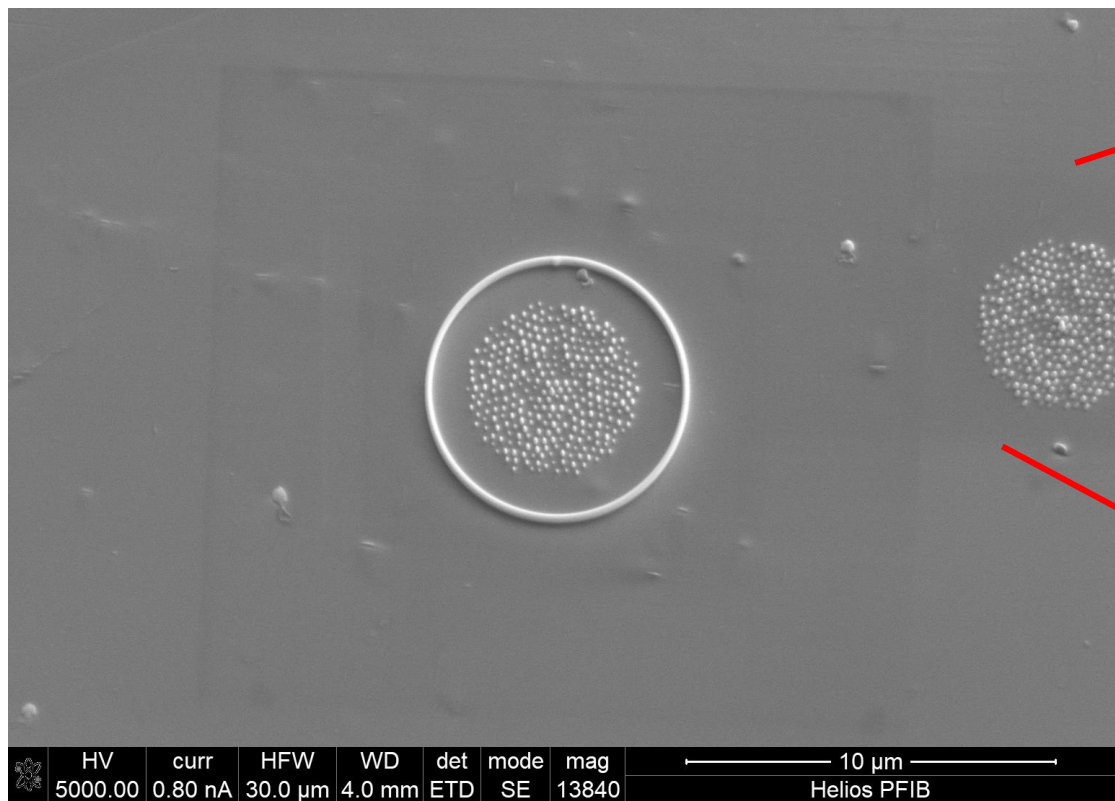
## Autres paramètres

- Macro pour boucle (image MEB - usinage FIB)
- Recaler le faisceau FIB : macro de suivi
- Recaler le faisceau MEB : imageJ en post-traitement
- Réduction de la re-déposition FIB
  - *Limiter courant FIB*
  - *Contour de protection*

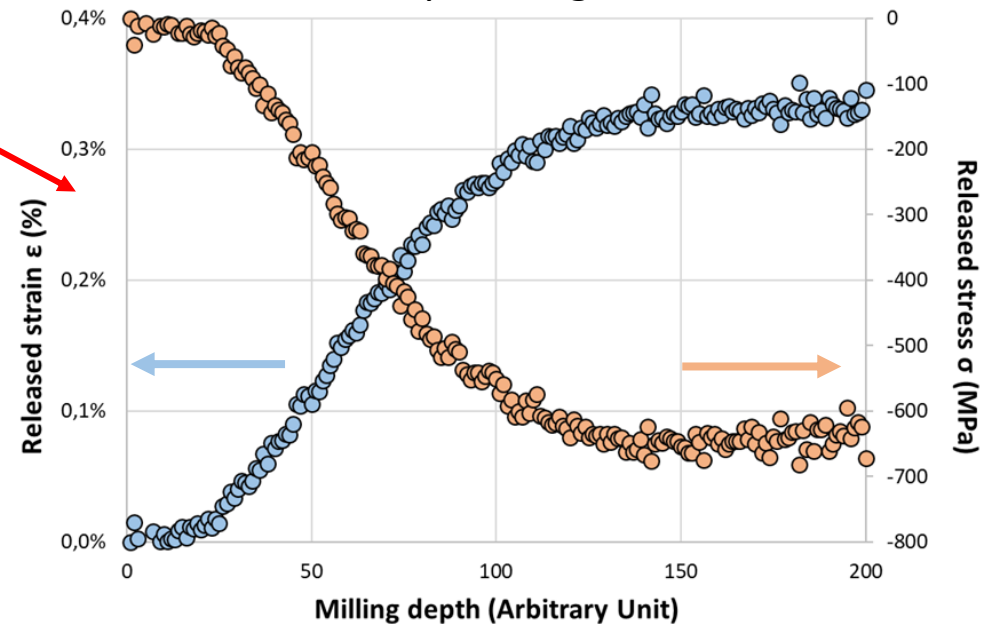


*Images MEB du re-dépôt et de l'intérêt du mur de protection*

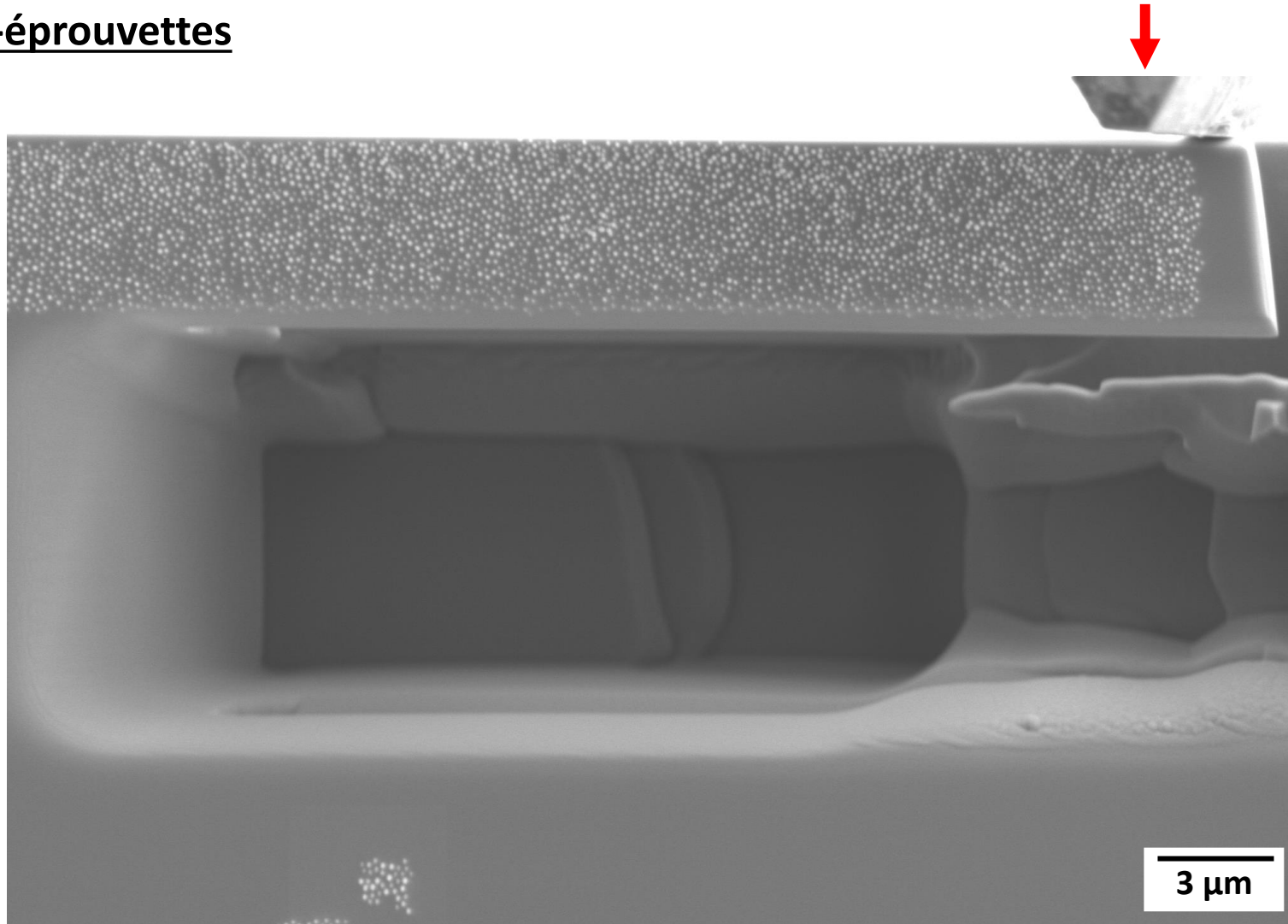
## Résultats

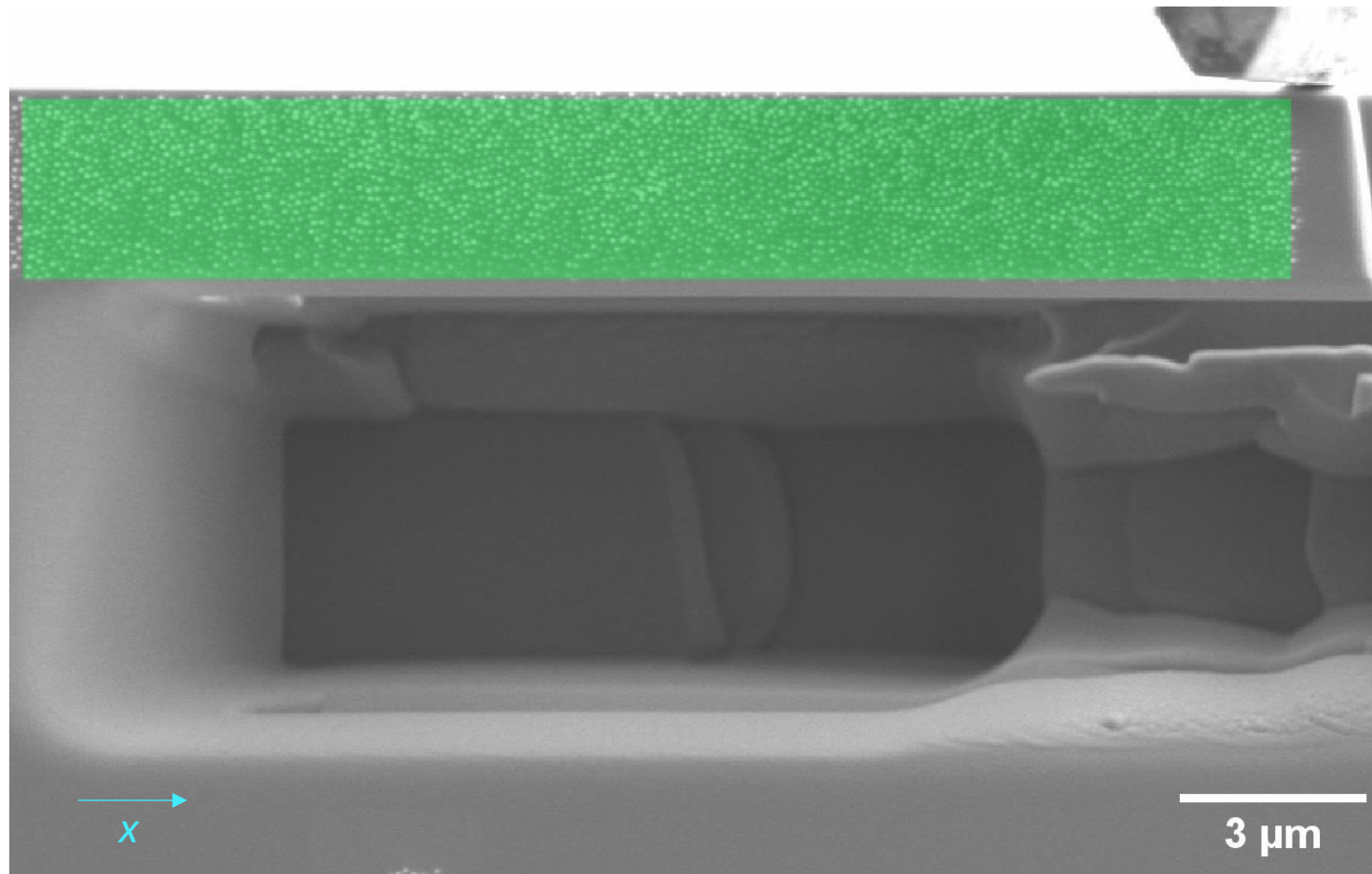


Mesures CIN du champs de déformation sur chaque image



## Mouchetis sur $\mu$ -échantillons



CIN sur flexion *in situ*

**MEB :**

**Microscope Électronique à Balayage**

**Essais in situ**

- Acquisition des images : compromis entre temps et qualité

**Corrélation d'images numériques :**

- Réalisation du mouchetis
- Acquisition des images

*Optimiser les paramètres*

**Merci pour votre attention**